EEMF7171 - Current Topics in Plasma Processing

**EEMF 7171** Current Topics in Plasma Processing (1 semester credit hour) Discussion of current literature on plasma processing; applications, diagnostics, sources, chemistry and technology. May be repeated for credit as topics vary (9 semester credit hours maximum). Must have knowledge of plasma processing technology. Prerequisites: EEMF 6383 or MECH 6383 or PHYS 6383 or equivalent and instructor consent required. (1-0) Y (2016-02-06 00:07:17)